REMARKS

The specification has been amended. Claims 15, 16, 24, and 29 have been amended. Claims 15 - 34 are pending in the application.

In the Office Action, the disclosure is objected to. Also, in the Office Action, claim 24 is rejected under 35 U.S.C. §112, second paragraph. Additionally, in the Office Action, claims 15-19, 21, and 26-33 are rejected under 35 U.S.C. 102(b) as being anticipated by Damrath US Patent No. 5,938,425. Furthermore, in the Office Action, claims 20, 34, 22-25 (24 as understood) are rejected under 35 U.S.C. 103(a) as being unpatentable over Damrath US Patent No. 5,938,425.

With respect to the objection to the disclosure, Applicants have Page 2 of the specification to delete the recitation of claim numbers. Thus, it is respectfully requested that the objection to the disclosure is now overcome.

With respect to the rejection of claim 24 under 35 U.S.C. §112, second paragraph, Applicants have amended claim 24 to delete the recitation of the term "possibly". Thus, it is respectfully requested that the rejection of claim 24 under 35 U.S.C. §112, second paragraph, is now overcome.

Applicants respectfully traverse the rejection of claims 15 - 34 under 35 U.S.C. 102(b) and §103(a) in view of the amendments of claim 15, 16, 24, and 29 and the following comments.

Claim 15 of the present application as currently amended recites a gas cooking apparatus including at least one gas burner, a control system for adjusting the heat output of the gas burner, and the control system includes at least one control organ arranged in a gas main leading to the gas burner. The gas cooking apparatus also includes the control system controlling the control organ to adjust a gas throughput supplied to a burner nozzle of the gas burner. As

further recited in claim 15 of the present application as currently amended, the gas cooking apparatus also includes at least one primary line communicated with the gas main and coupled to the burner nozzle via the control organ such that the control organ controls the gas throughput supplied through the primary line to the burner nozzle and the path of gas supplied through the primary line via the control organ to the burner nozzle having a flow resistance greater than a flow resistance formed by the burner nozzle. Additionally, the gas cooking apparatus includes at least one secondary line coupled to the burner nozzle in parallel to the control organ. The secondary line includes an allocated shut-off organ for opening and closing the secondary line and the secondary line formed to have a flow resistance which restricts the gas throughput in the secondary line, the flow resistance being lower than a flow resistance formed by the burner nozzle.

Damrath US Patent No. 5,938,425 discloses a gas supply pipe 1 supplied by a gas main, a gas tank or a gas cylinder for the controlled supply of gas according to the invention to a burner nozzle 3, which is the integral part of a burner 2, which can be installed e.g. in a gas cooker or gas baking oven. The gas supply pipe 1 branches into four partial gas pipes 10, 20, 30, 40 connected in parallel, which subsequently recombine to form a burner supply pipe 5 connected to the burner nozzle 3. The partial gas pipes 10, 20, 30, 40 each have a control unit for control of the partial gas flows and the control units each comprise a switching element 11, 21, 31, 41 and a throttle element 12, 22, 32, 42.

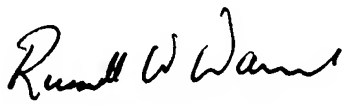
It is submitted that Damrath US Patent No. 5,938,425 fails to teach or disclose a gas cooking apparatus as recited in claim 15 of the present application as currently amended. For example, Damrath US Patent No. 5,938,425 fails to teach or disclose a primary line to the burner nozzle with the path of gas supplied through the primary line having a flow resistance greater than a flow resistance formed by the burner nozzle and, additionally, a secondary line formed to have a flow resistance lower than a flow resistance formed by the burner nozzle Instead, the gas pipes 10, 20, 30, 40 are all formed to have a flow resistance

lower than a flow resistance formed by the burner nozzle but there is no teaching or disclosure of a primary line having a flow resistance greater than a flow resistance formed by the burner nozzle.

Thus, it is accordingly believed that Damrath US Patent No. 5,938,425 neither shows nor suggests the gas cooking apparatus of the present invention as recited in claim 15 of the present application as currently amended and the method as recited in claim 29 of the present application as currently amended. Claims 15 and 29 of the present application as currently amended are, therefore, believed to be patentable over the prior art and, since claims 16 - 28 are ultimately dependent, respectively, on claims 1, 9, and 17 of the present application as currently amended, since claims 16 - 28 are ultimately dependent on claim 15 of the present application as currently amended and claims 31 - 34 are ultimately dependent on claim 29 of the present application as currently amended, it is submitted that claims 16 - 28 and claims 31 - 34 are patentable for at least the reason that claims 15 and 29 are patentable.

In view of the foregoing, reconsideration and allowance of claims 15 - 34 is respectfully solicited.

Respectfully submitted,



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